

**INFORMATION DISCLOSURE
STATEMENT BY
APPLICANTS
PTO FORM 1449**

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Applicant(s)
BENZEL et al.

Filing Date
Herewith

Group
To Be Assigned

U.S. PTO
10/29/01
10401772
JES

U. S. PATENT DOCUMENTS

| EXAMINER'S INITIALS | PATENT NUMBER | PATENT DATE | NAME | CLASS | SUBCLASS | FILING DATE |
|---------------------|---------------|--------------|------------|-------|----------|-------------|
| N | 5,714,791* | Feb. 3, 1998 | CHI et al. | | | |
| | | | | | | |

* Described in the Specification.

FOREIGN PATENT DOCUMENTS

| EXAMINER'S INITIALS | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUB-CLASS | TRANSLATION | |
|---------------------|-----------------|---------------|---------|-------|-----------|-------------|----|
| | | | | | | YES | NO |
| H | WO 96 05506* | Feb. 22, 1996 | PCT | | | | |
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* Described in the Specification.

OTHER DOCUMENTS

| EXAMINER'S INITIALS | AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC. |
|---------------------|--|
| M | D. Heinze, <i>Semiconductor Technologies for Manufacturing Modern Moisture Sensors</i> , Sensor 91, Nuremberg 1991, Kongressband (Convention Volume) IV, 112-121).* |
| M | Lammel et al., <i>Free-standing Mobile 3D Microstructures of Porous Silicon</i> , Proceedings of the 13th European Conference on Solid-State Transducers, Eurosensors XIII, The Hague, 1999, 535-536.* |
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* Described in the Specification.

| EXAMINER | DATE CONSIDERED |
|----------|-----------------|
| | 11-7-02 |

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.